

Serial No.

Docket No.: RD-25,993-7



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Barry Lee-Mean Yang et al.
Serial No.:
Filed:
Group Art Unit:

For: MULTILAYER ARTICLE AND METHOD OF MAKING BY ARC PLASMA DEPOSITION

INFORMATION DISCLOSURE STATEMENT

Honorable Assistant Commissioner of Patents
Washington, DC 20231

SIR:

This Information Disclosure Statement is being filed under 37 C.F.R. §1.56 for a Continuation Application, which relies on the filing date of its parent application, such parent application being identified as:

U.S. Patent Application Serial No: 09/271,654

Examiner: M. Padgett

Filed: March 17, 1999

Allowed Date: 11/7/01

Inventor(s): Barry Lee-Mean Yang et al.

Issue Batch No. O58

Title: MULTILAYER ARTICLE AND METHOD OF MAKING BY ARC PLASMA DEPOSITION

Enclosed are copies of forms PTO-1449 and PTO-892 listing all "prior art" cited and submitted in the parent application. Pursuant to 37 C.F.R. §1.98(d), no actual copies of the documents listed are being furnished to the PTO with this Information Disclosure Statement.

Respectfully submitted,

A handwritten signature in black ink, appearing to read 'Robert P. Santandrea'.

Robert P. Santandrea
Attorney

DATE: December 4, 2001

REGISTRATION NO: 45,072
TELEPHONE: (518) 387-6304

**General Electric Company
CRD Patent Docket Room 4A59
PO Box 8, Bldg. K-1 Salamone
Schenectady, New York 12301**

Applicant

Barry Lee-Mean Yang et al.

Filing Date

03/17/99

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2761

JC821 U.S. PTO
10/04/607
01/16/02

INFORMATION DISCLOSURE STATEMENT BY APPLICANT--

LIST OF ITEMS

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA	3	1	6	1	6	1	5	12/15/64	Goldberg			
AB	3	2	2	0	9	7	3	11/30/65	Goldberg			
AC	3	3	1	2	6	5	9	04/04/67	Kurkjy et al.			
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AK	4	2	1	0	6	9	9	07/01/80	Schroeter et al.			

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	BA	4	2	2	4	3	7	8	09/23/80	Schroeter et al.			
	BB	4	2	4	2	3	8	1	12/30/80	Goossens et al.			
	BC	4	4	5	4	2	7	5	06/12/84	Rosenquist			
	BD	4	8	4	2	9	4	1	06/27/89	Devins et al.			
	BE	4	8	7	1	5	8	0	10/03/89	Schram et al.			
	BF	4	9	2	7	7	0	4	05/22/90	Reed et al.			
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	BK	5	2	9	8	5	8	7	03/29/94	Hu et al.			

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	BL								
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OTHER INFORMATION (Including Author, Title, Date, Pertinent pages. Etc.)

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	CC	5	4	6	3	0	1	3	10/31/95	Tokuda et al		
	CD	5	4	8	0	7	2	2	01/02/96	Tomonaga et al.		
	CE	5	4	9	4	7	1	2	02/27/96	Hu et al.		
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	CH	5	6	3	5	0	8	7	06/03/97	Schiller et al.		
	CI	5	7	1	8	9	6	7	02/17/98	Hu et al.		
	CJ											
	CK											

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	CP							

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